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FORM PTO-1449  <b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b>  (use several sheets if necessary)	SERIAL NO. Not yet assigned	ATTORNEY DOCKET NO. SJO920000160US1
	FILING DATE August 20, 2001	GROUP ART UNIT 2652
	APPLICANT(S): Jeffrey S. Lille	

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINE R INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLAS S	FILING DATE
Chen	A1	5,959,801	09/28/99	Gillis et al.	360/75	10/22/97
	A2	5,856,967	01/05/99	Mamin et al.	369/126	08/27/97
	A3	5,764,432	06/09/98	Kasahara	360/75	01/24/96
	A4	5,745,319	04/28/98	Takekado et al.	360/78.05	04/27/95
Chen	A5	4,814,908	03/21/89	Schmitz	360/77.02	12/03/86

## FOREIGN PATENT DOCUMENTS

EXAMINE R INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION	
						YES	NO
Chen	A6	JP4-157685	05/29/92	Japan	G11B24/24		X
	A7	JP62-3476	01/09/87	Japan	G11B24/24		X
	A8	JP59-203272	11/17/84	Japan	G11B24/40		X
Chen	A9	EP 242 597	10/28/87	Europe	G11B21/20	X	

## NON-PATENT DOCUMENTS

EXAMINE R INITIAL		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)
Chen	A10	K. H. Stokes and R. B. Watrous, "Magnetic Head with Piezoelectric Positioning", Vol. 16 No. 5, October 1973, p. 1429.
Chen	A11	G. Elsner, H. Hinkel and E. Prinz, "Magnetic Head with Retractable R/W Element", Vol. 27 No. 7B, December 1984, pp. 4573-4574.

EXAMINER <i>Chen Tarp</i>	DATE CONSIDERED <i>03/26/04</i>
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).

<i>Chen</i>	A12	Bruce D.S. Chou, Chang-Nan Chen and Jin-Shown Shie, "Micromachining on (111)-Oriented Silicon", Sensors and Actuators 75 (1999) 271-277.
<i>Chen</i>	A13	John H. Comtois, M. Adrian Michalick and Carol Craig Barron, "Electrothermal Actuators Fabricated in Four-level Planarized Surface Micromachined Polycrystalline Silicon", Sensors and Actuators A 70 (1998) 23-31.

EXAMINER <i>Chen Tzeng</i>	DATE CONSIDERED <i>03/26/04</i>
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).